

## Local Variation of Magnetic Parameters of the Free Layer in TMR Junctions

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Local M-H loops have been measured on the free layer of a tunneling magnetoresistance (TMR) junction using the magneto-optical Kerr effect (MOKE) system, with an optical beam size of about 2  $\mu\text{m}$  diameter. Tunnel junctions were deposited using the DC magnetron sputtering method in a chamber with a base pressure of  $3 \times 10^{-9}$  Torr. The relatively irregular variations of coercive force  $H_c$  ( $\sim 17.5$  Oe) and unidirectional anisotropy field  $H_{ua}$  ( $\sim 7.5$  Oe) in the as-deposited sample are revealed. After 200 °C annealing,  $H_c$  decreases to 15 Oe but  $H_{ua}$  increases to 20 Oe with smooth local variations. Two-dimensional plots of  $H_c$  and  $H_{ua}$  show the symmetric saddle shapes with their axes aligned with the pinned layer, irrespective of the annealing field angle. This is thought to be caused by geometric effects during deposition, together with a minor annealing effect. In addition, the variation of root mean square (RMS) surface roughness reveals it to be symmetric with respect to the center of the pinned-layer axis, with the roughness of 2.5 Å near the edge and 5.8 Å at the junction center. Comparison of surface roughness with the variation of  $H_{ua}$  suggests that the  $H_{ua}$  variation of the free layer is well described by dipole interactions related to surface roughness. As a whole, the reversal magnetization is not uniform over the entire junction area and the macroscopic properties are governed by the average sum of local distributions.

**Key words :** Coercivity, Exchange coupling, MOKE, Surface roughness, TMR

### 1. Introduction

Magnetic tunnel junctions (MTJs) consisting of two ferromagnetic layers separated by a thin insulating layer (typically  $\text{Al}_2\text{O}_3$ ) show large tunneling magnetoresistance (TMR), which makes them promising candidates for magnetic random access memory (MRAM) devices [1, 2]. As is generally known [3, 4], the tunneling resistance will be large in a field regime, with antiparallel magnetizations of the two layers. For all other field regimes, the magnetizations in both electrodes are parallel and the resistance will have a lower value. Thus, resistance characteristics are governed by the ferromagnetic-anti-ferromagnetic states of the two magnetic layers during cyclic magnetization. Most researchers have dealt with the materials and fabrication parameters controlling the coercive forces and exchange coupling caused by interlayer coupling [5, 6], rather than examining the way in which magnetization reversal governs magnetoresistance

(MR) characteristics.

The magnetization reversal in a stack of thin films may be strongly affected by various magnetic parameters. One important parameter is unidirectional anisotropy (the exchange coupling) caused by the interlayer coupling between adjacent films. The main interlayer coupling effects have been identified to be RKKY-like coupling through an indirect exchange mediated by the itinerant electrons, and Neel's orange peel coupling from magnetic dipole interaction related to interfacial morphological corrugations [7-9]. When an insulating layer prevents electron itinerancy, dipole interaction is reasonable, rather than RKKY-like coupling.

The dipole interaction is a function of the correction length, the height of the sinusoidal roughness of the interface surface, and the thickness of each magnetic layer [10]. Even though interface roughness of NiFe/MnIr, measured by the XRD method, is not equal to surface roughness measured by the atomic force microscope, there is quantitative agreement between them [11]. However, there are contradictory results for the correlation between exchange coupling and surface roughness; while

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one result indicates that the exchange coupling is inversely proportional to surface roughness [11, 12], another result claims that the exchange coupling is proportional to surface roughness [13]. A full understanding of their relationship has not been attained, because of the complicated material and magnetic parameters.

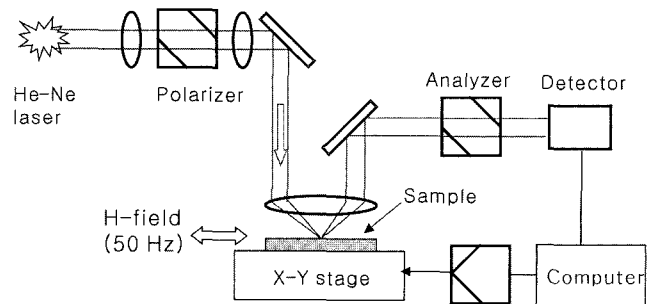
In reality, because of the inhomogeneity of material parameters, magnetization in both magnetic layers can be nonuniform over the sample with a corresponding distribution of reversals. This distribution probably arises from local variations in magnetic anisotropy and/or coupling from grain to grain within each layer. The magnetization reversal distribution could play a decisive role in the MR ratio and its field sensitivity. However, very few papers have reported MR dependence on exchange coupling strength between two magnetic layers, and the intrinsic pinning field governing magnetization reversal [14, 15]. In this work, we have measured the local distributions of coercive forces, as well as uniaxial anisotropy and surface roughness on MTJs prepared using DC sputtering. We discuss the measured magnetic parameters as functions of surface roughness and the annealing field angle.

## 2. Experimental Procedure

Tunnel junctions with the structure of Ta (50 Å)/Cu (100 Å)/Ta (50 Å)/Ni-Fe (20 Å)/Cu (50 Å)/Mn<sub>75</sub>Ir<sub>25</sub> (100 Å)/Co<sub>70</sub>Fe<sub>30</sub> (25 Å)/Al-O/Co<sub>70</sub>Fe<sub>30</sub> (25 Å) were prepared on thermally oxidized Si wafers using DC magnetron sputtering in a chamber with a base pressure of  $3 \times 10^{-9}$  Torr. For barrier formation, a 15-Å-thick metallic Al film was deposited and subsequently oxidized in an oxidation chamber with a radial line slot antenna (RLSA) for 2.45-GHz microwaves [16]. Kr was used as the inert gas mixed with O<sub>2</sub> molecular gas for the plasma oxidation. In-situ patterned junctions were prepared using a shadow mask during deposition. The junction size was  $180 \times 180 \mu\text{m}^2$ .

The junction samples were thermally annealed at 200 °C for 1 hour under a magnetic field of 1 kOe, followed by field cooling. The angle  $\theta_a$  between the annealing field and the pinned-layer axis varied from 0° to 90°. The transport measurement was performed with a four-point probe method at room temperature for samples with electrode layers of 1000-Å NiFe, deposited on the free layer Co-Fe. In these samples, the maximum TMR ratio was measured to be 40% in a 270 °C field-annealed sample.

The magneto-optical Kerr effect (MOKE) method was used to obtain the local M-H loops under a 50 Hz driving field, as depicted in Fig. 1. The penetration depth using He-Ne laser light was about 30 nm, which was enough to



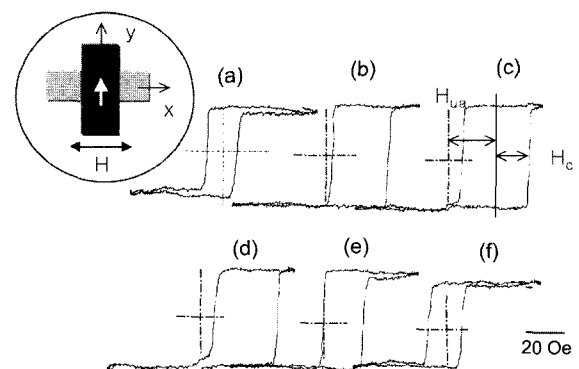
**Fig. 1.** Schematic view of micro-MOKE (magneto-optical Kerr effect) system.

affect the whole thickness of the free layer. The field was applied in the annealing field direction. The maximum field amplitude was 100 Oe, which was enough to saturate the free layer in the multilayer structure. The laser beam size was about  $2 \mu\text{m}$  diameter, corresponding to the spatial resolution of the micro-MOKE system. The sample was scanned using a computer-controlled x-y stage to obtain a two-dimensional plot of magnetic parameters. Surface roughness was measured by atomic force microscopy (AFM) at different points across the junction.

## 3. Results and Discussion

### 3.1. Local variation

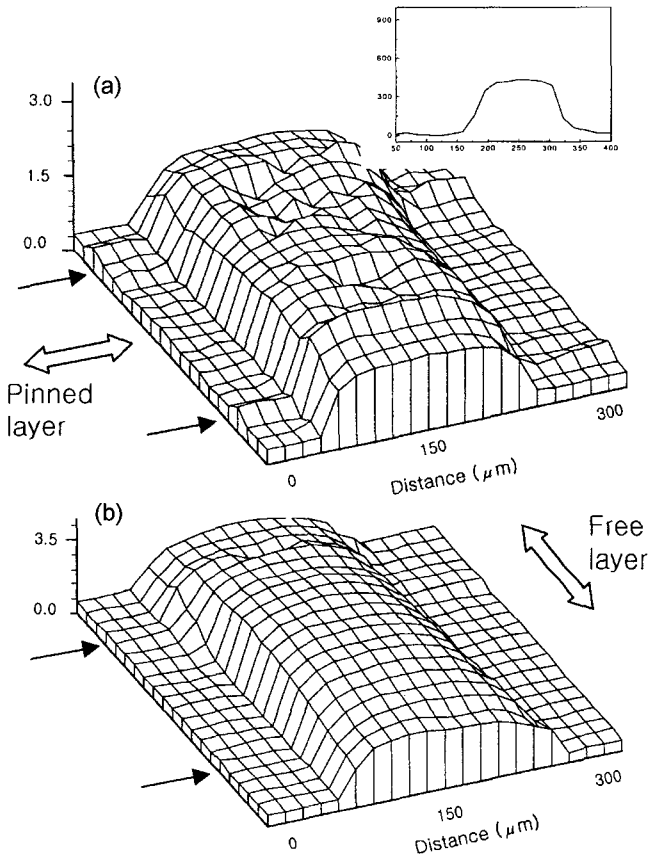
Figures 2(a)-(f) show the measured M-H loops at several positions along the free-layer direction (y-axis), as depicted in the inset. Here, the sample was annealed once at a temperature of  $T_a = 200$  °C and the annealing field angle  $\theta_a = 0^\circ$ . The M-H loop was measured under a cyclic field along the pinned-layer direction, that is, the annealing field direction. There is no shift of loop at the outside edge of the junction, as shown in Fig. 2(a). The



**Fig. 2.** M-H loops along the free-layer direction (y-axis), at the positions (a) 0, (b) 105, (c) 130, (d) 165, (e) 205, and (f) 285  $\mu\text{m}$ . The starting point is 50  $\mu\text{m}$  below the junction edge.

shift due to the unidirectional anisotropy (bias) field  $H_{ua}$  increases as the measuring point moves to the junction center, as shown in Figs. 2(b) and (c), but then decreases as the point moves away from the center. We can also see similar variation of the coercive force  $H_c$ . Even though there are local variations of both  $H_c$  and  $H_{ua}$ , the squareness ratio of the loops is nearly equal to one, except for the loops caused by demagnetizing effects when the measuring point is less than about  $10 \mu\text{m}$  distant from the edge boundary.

Two-dimensional plots of maximum amplitude of Kerr signal, obtained using a  $20 \times 20$  scan, are shown in Figs. 3(a), (b) for as-deposited and  $200^\circ\text{C}$ -annealed samples, respectively. The signal of MOKE could be affected by the experimental parameters of extinction ratio of polarizer, optical reflectivity and analyzer angle, and by material parameter of Kerr rotation. Because the experimental parameters are fixed during the measurement, maximum Kerr signal corresponds with the maximum magnetization of free layer. There is an irregular variation

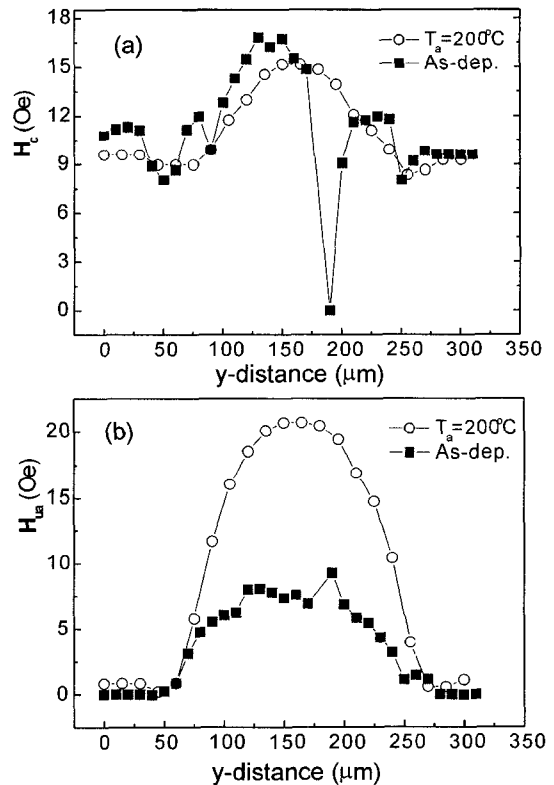


**Fig. 3.** Two-dimensional distribution of maximum magnetization (a) as-deposited (b)  $200^\circ\text{C}$ -annealed sample for the annealing field angle  $\theta_a = 0^\circ$ . (Inset figure: variation of film thickness across the junction center, checked by  $\alpha$ -stepper.)

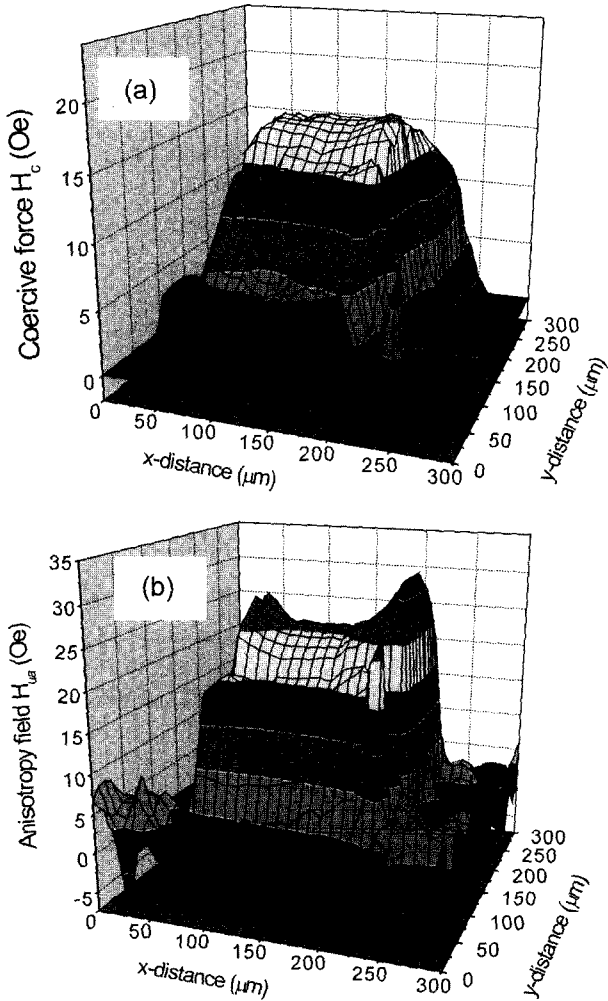
of maximum Kerr signal in the as-deposited sample even near the center of the free layer. There is also a gradual increase from edge, and it reaches 90% of the center value at  $30 \mu\text{m}$  distance from the boundary. This variation is caused by the gradual change of film thickness arising from edge effects during deposition using a mask. The thickness variation was checked by the  $\alpha$ -stepper as shown in the inset figure. After annealing, the irregular variation becomes smooth out over the junction area except in the edge region.

The variations of  $H_c$  and  $H_{ua}$  for an annealed sample are compared with those for an as-deposited one in Figs. 4(a) and (b), respectively. The  $H_c$  in the as-deposited sample is about 10 Oe outside the junction, and a maximum of 17.5 Oe at the junction center. The local variation is quite irregular, with changes of 5 Oe, as shown in Fig. 4(a). As a whole,  $H_c$  is reduced after field annealing, while the local variation becomes smooth and reveals symmetry with respect to the center of the pinned-layer axis.  $H_c$  decreases with annealing temperature up to  $250^\circ\text{C}$ , and then is nearly constant.

In Fig. 4(b),  $H_{ua}$  is induced during the sample deposition, with a maximum of 7.5 Oe at the junction center in



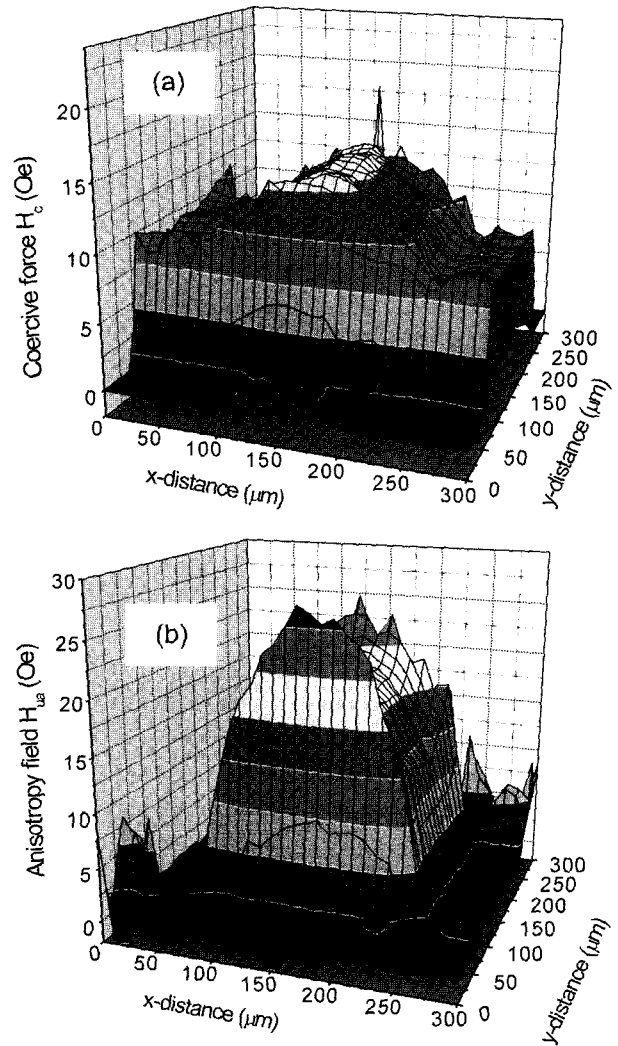
**Fig. 4.** Variation of (a) coercive force  $H_c$  and (b) unidirectional bias field  $H_{ua}$  along the free-layer axis in as-deposited and  $200^\circ\text{C}$ -annealed samples.



**Fig. 5.** Two-dimensional distribution of (a) coercive force  $H_c$ , and (b) unidirectional anisotropy field  $H_{ua}$  in 200 °C-annealed sample for the annealing field angle  $\theta_a = 0^\circ$ . (x-axis: pinned layer, y-axis: free-layer directions)

the as-deposited sample and irregular variation. However, the field annealing enhances the  $H_{ua}$  up to 20.5 Oe at the center. Similarly to  $H_c$ ,  $H_{ua}$  shows smooth variation along the free layer; that is, the zero-value of  $H_{ua}$  gradually increases to 25 Oe at the junction center. As we describe later, magnetic dipole interaction between the free and pinned layers is an origin of  $H_{ua}$ . Thus, the above-described changes of  $H_{ua}$  might be influenced by the changes of the exchange anisotropy of *pinned layer* during field annealing. The bias field of the antiferromagnetic layer is known to be a function of the MnIr thickness and the annealing temperature [17]. For 100-Å MnIr thickness, the exchange anisotropy gradually increases with increasing annealing temperature up to  $T_a = 400$  °C.

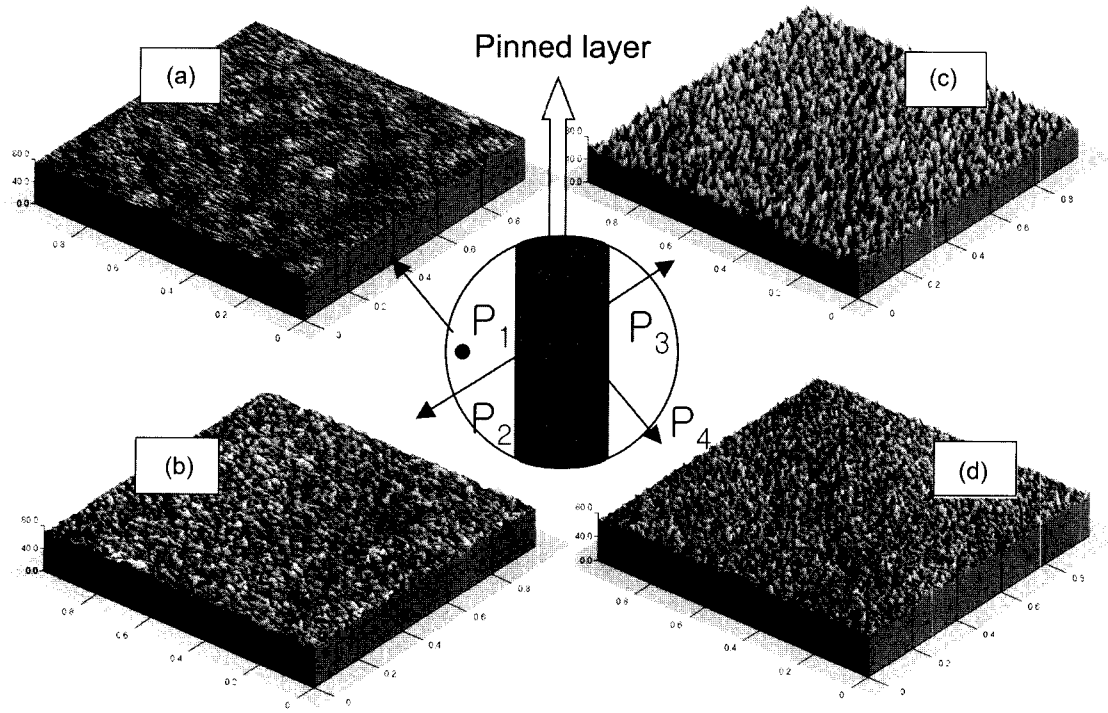
Figures 5(a) and (b) are two-dimensional plots of  $H_c$  and  $H_{ua}$ , respectively, on the annealed sample for  $T_a = 200$



**Fig. 6.** Two-dimensional distribution of coercive force  $H_c$  and unidirectional anisotropy field  $H_{ua}$  in 200 °C-annealed sample for the annealing field angle  $\theta_a = 90^\circ$ . (x-axis: free layer, y-axis: pinned layer directions)

°C, where measuring points are scanned over the entire junction area. Both  $H_c$  and  $H_{ua}$  show a saddle shape with its axis along the pinned-layer axis, where local variations along the pinned-layer axis are relatively small, compared to those in the free-layer direction. As a whole, local variations of  $H_c$  and  $H_{ua}$  over the junction area are significant compared to the maximum magnetization.

When the sample is annealed under a magnetic field in the free-layer axis, that is,  $\theta = 90^\circ$ , the M-H loops measured on the free- and pinned-layer axes clearly reveal the change of the magnetically easy axis according to the annealing field. Figure 6 shows the two-dimensional distribution of  $H_c$  and  $H_{ua}$ , where the loops are measured under the field in the free-layer axis. The local distributions of  $H_c$  and  $H_{ua}$  also show saddle shapes with their



**Fig. 7.** AFM images across the pinned layer outside the junction, (a) at point p1, outside the layer, (b) point p2, near left edge, (c) point p3, center, and (d) point p4, near right edge. (scan area:  $1 \times 1 \mu\text{m}^2$ )

axes along the pinned layer. That is, the easy axis is governed by the annealing field direction while the saddle axis is always directed along the pinned-layer axis. These results indicate that the saddle shapes of  $H_c$  and  $H_{ua}$  are basically related to geometric effects during sample deposition.

### 3.2. Surface roughness

AFM images across the pinned layer outside the junction are shown in Figs. 7(a)~(d), at the measuring points p1-p4 depicted in the inset. At point p1, outside the layer, the root mean square (RMS) roughness is  $1.4 \text{ \AA}$ , corresponding to the surface roughness of the Si substrate. Within the layer, the roughness increases to  $2.5 \text{ \AA}$  at p2 near the edge, and  $5.5 \text{ \AA}$  at p3 near the center of the layer, but then decreases to  $2.7 \text{ \AA}$  near the left edge (p4).

Figures 8(a)~(d) are AFM images at several measuring points along the free layer across the junction. On the free layer outside the junction (point p5), RMS roughness is  $3.3 \text{ \AA}$ , and becomes smaller,  $2.3 \text{ \AA}$ , at the near edge (p6). The roughness increases to  $5.7 \text{ \AA}$  as the measuring point moves to the center of the junction (p7), and then decreases as the point moves to the left edge (p8).

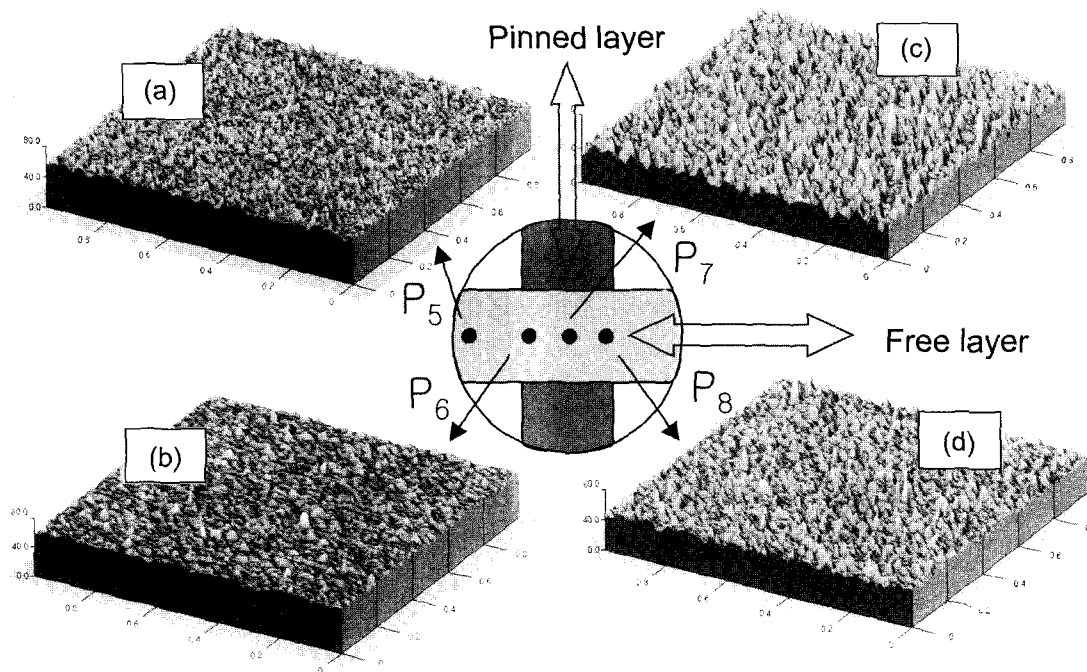
Figures 9(a) and (b) show the plot of RMS roughness versus measuring distance across the pinned layer, obtained from Figs. 7 and 8, respectively. The range of variation

of RMS roughness is nearly the same, from  $2.5 \text{ \AA}$  to  $5.8 \text{ \AA}$ , and reveals symmetric variation with respect to the center of the pinned-layer axis. However, the variation near the edge is greater when roughness is measured on the free layer across the junction. Here, it is noted that the flatness at the edge point (p6) is better than that on the free-layer region (p5). These variations are quite similar to those of film thickness, as shown in the inset figures. This may be a geometric effect of the deposition process using a shadow mask, but it is hard to understand its mechanism in detail.

In Figs. 5(b) and 6(b), the  $H_{ua}$  distribution shape represents the amount of coupling between layers. The  $H_{ua}$  ( $\sim 20 \text{ Oe}$ ) at the junction center is about 4 times that near the edge ( $\sim 5 \text{ Oe}$ ). There is an insulating  $\text{Al}_2\text{O}_3$  layer between the free and pinned (and antiferromagnetic) layers. Thus, Neel's orange peel coupling by dipole interaction could be dominant over RKKY-like interaction. The exchange coupling  $H_N$  is generally expressed as [10]:

$$H_N = \frac{\pi^2 h^2}{\sqrt{2} t_F \lambda} M_p \exp(-2\pi\sqrt{2} t_S / \lambda) \quad (1)$$

where  $h$  and  $\lambda$  are the height and wavelength of the sinusoidal roughness respectively,  $t_F$  and  $t_S$  are the thickness of the free layer and the distance between two



**Fig. 8.** AFM images along the free layer across the junction, (a) at point p5, outside the layer, (b) point p6, near left edge, (c) point p7, junction center, and (d) point p8, near right edge. (scan area:  $1 \times 1 \mu\text{m}^2$ )

layers respectively, and  $M_p$  is the saturation magnetization of the pinned layer.

The  $M_p$  could be constant regardless of pinned layer thickness. When thickness  $t_F$  is taken into account in denominator, the small increase of at both edges of junction along pinned layer, in Figs. 5(b) and 6(b), is described by the decreasing  $t_F$  at edges. But along free layer could be decreased inside the junction area, opposite tendency to measured one along pinned layer. Because the exchange coupling is given as a square function of roughness height  $h$ , the coupling at the junction center along free layer is expected to be 4-5 times that near the edge from the roughness shown in Fig. 9. There is good agreement between the measured and expected  $H_{ua}$  variations, suggesting that  $H_{ua}$  in the free layer is well described by dipole interaction between the free and pinned layers.

### 3.3. Annealing field effect

The variations of  $H_c$  and  $H_{ua}$  are compared in Figs. 10(a)~(c) for annealing field angles  $\theta_a = 0^\circ, 45^\circ,$  and  $90^\circ$ , respectively. Here, the loops are measured in a field along the annealing field direction, and the legends of x-axis mean the distance along the measured directions. For the  $45^\circ$  annealed sample, both  $H_c$  and  $H_{ua}$  have a relative plateau regime over the junction area, compared to the  $\theta = 0^\circ, 90^\circ$  samples. It is not easy to evaluate the annealing field effect clearly, but topological distribution of

magnetization reversals could discriminate its effect.

The reversal field  $H_r$  for increasing fields is approximated by the sum of  $H_c$  and  $H_{ua}$ , and the reversal field  $H_r$  for decreasing fields is the difference between  $H_c$  and  $H_{ua}$ , i.e.,  $H_{ua} - H_c$  [15]. The sum of  $H_c$  and  $H_{ua}$  could reflect the distribution of reversal field in an increasing field. Thus, the topological distribution of the reversal field is obtained by sorting the sum of  $H_c$  and  $H_{ua}$ .

Figure 11 shows the distribution of the sum of  $H_c$  and  $H_{ua}$ , that is, the topological distribution of the reversal field, where the lines represent Gaussian fitting curves for corresponding data. The field for maximum counter number are 40 Oe, 35 Oe, and 35 Oe for annealing field angles  $\theta_a = 0^\circ, 45^\circ,$  and  $90^\circ$ , respectively. However, the field regime for full width at half maximum on the  $\theta_a = 45^\circ$  sample is relatively small, at about 8 Oe. This suggests that there is some effect of the annealing field angle on reversal magnetization, and that its distribution is relatively narrow for the  $45^\circ$  sample, compared to the  $\theta_a = 0^\circ$  and  $90^\circ$  samples.

### 3.4. Average of local distribution

When the beam size is expanded over the entire junction area, the measured M-H loop should reflect the average of the local distribution. Figure 12 shows the M-H loop for expanded beam size over the junction area on an annealed sample with  $\theta_a = 0^\circ$ . Here, two loops are superimposed: one loop without shift corresponds to the

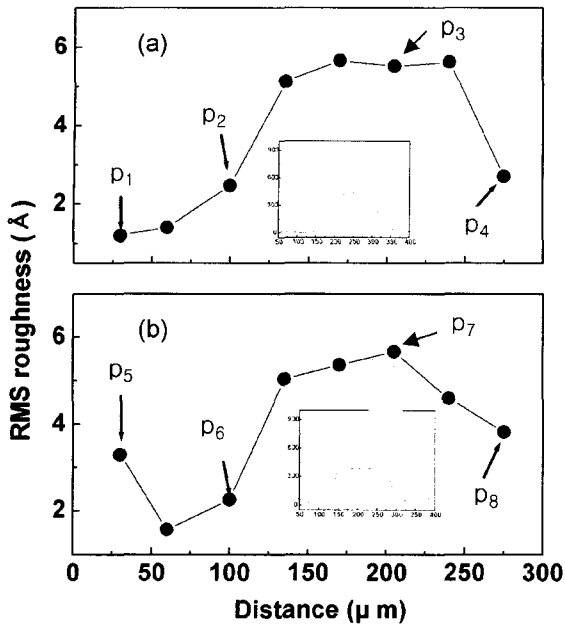


Fig. 9. Variation of average surface roughness (a) across the pinned layer outside junction and (b) inside junction.

area outside the junction along the free-layer axis, and another loop with shift corresponds to the area inside the junction. Even in the loop for the junction, the field regime for magnetization reversal is wide; that is, the magnetization reversal starts from 35 Oe and ends at 45 Oe. This regime of reversal distribution is in agreement with the value obtained from the topological distribution in Fig. 11(a). This agreement suggests that magnetization is not uniform over an entire junction area, and that macroscopic properties are governed by the averages of their local distributions.

### 4. Conclusion

Local M-H loops have been measured on the free-layer of TMR junctions using a MOKE system, where the optical beam size is about 2 μm diameter. Tunnel junctions were deposited using a DC magnetron sputtering method in a chamber having a base pressure of 3×10<sup>-9</sup> Torr. There is a gradual increase of magnetization as the measuring point moves inwards from the edge, due to the gradual change of film thickness. Irregular variations are revealed in as-deposited samples even near the center, but the magnetization is smoothed out over the junction area after annealing.

Relatively irregular variations of coercive force  $H_c$  (~17.5 Oe) and unidirectional anisotropy field  $H_{ua}$  (~7.5 Oe) in as-deposited samples are revealed. After annealing at 200 °C,  $H_c$  decreases to 15 Oe, but  $H_{ua}$  increases to 20

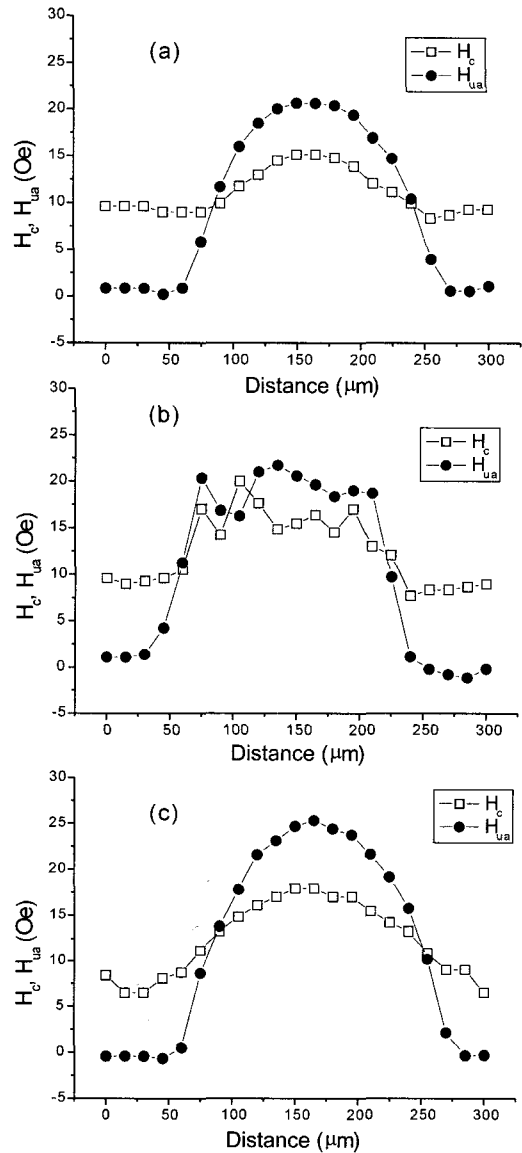
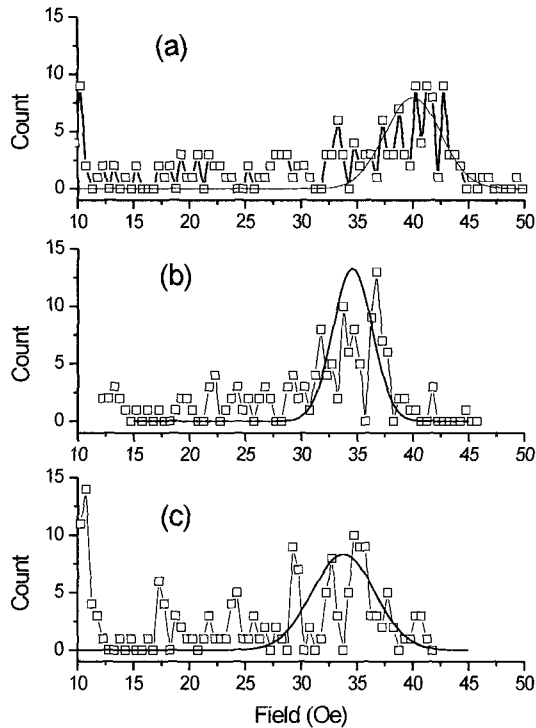


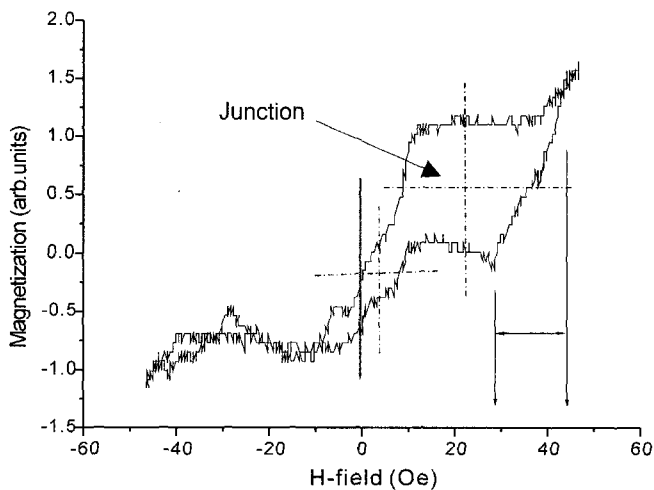
Fig. 10. Variations of  $H_c$  and  $H_{ua}$  in 200 °C-annealed sample for angles  $\theta_a = 0^\circ, 45^\circ,$  and  $90^\circ$ , respectively. The legend of x-axis means the distance along the measured directions.

Oe with smooth local variations. Two-dimensional plots of  $H_c$  and  $H_{ua}$  show symmetric saddle shapes with their axes on the pinned layer, irrespective of the annealing field angle, due to the geometric effect during deposition together with a minor annealing effect. In addition, the variation of RMS surface roughness is revealed to be symmetric with respect to the center of the pinned-layer axis, 2.5 Å near the edge and 5.8 Å at the junction center.

$H_{ua}$  could be uniform over the junction area when thickness is taken into account in dipole interactions. However, roughness is involved in dipole interactions, so the coupling at the junction center is expected to be 4-5 times that at the near edge. There is good agreement



**Fig. 11.** Topological distribution of reversal field  $H_r = H_c + H_{ua}$ , for angles  $\theta_a = 0^\circ$ ,  $45^\circ$ , and  $90^\circ$ , respectively, where the lines represent Gaussian fitting curves for corresponding data.



**Fig. 12.** M-H loop for expanded light beam over entire junction area in 200 °C-annealed sample for the annealing field angle  $\theta_a = 0^\circ$ . (Two loops are superimposed; one corresponding to the free layer outside the junction, and the other to the junction.)

between the measured and expected  $H_{ua}$  variations, suggesting that  $H_{ua}$  of the free layer is well described by dipole interaction between the free and pinned layers, and/or the antiferromagnetic MnIr layer. As a whole, the reversal magnetization is not uniform over the entire junction area and macroscopic properties are governed by the averages of the local distributions.

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